

PTO/SB/08A (07-05)

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Substitute for form 1449/PTO

INFORMATION DISCLOSURE STATEMENT BY APPLICANT

(Use as many sheets as necessary)

Sheet 1

of 2

Complete if Known

Application Number	10/555,341
Filing Date	10/28/2005
First Named Inventor	Jan Watte et al.
Art Unit	2874
Examiner Name	
Attorney Docket Number	TYR-P0002

U. S. PATENT DOCUMENTS

[illegible]

FOREIGN PATENT DOCUMENTS

Examiner Initials*	Cite No. ¹	Foreign Patent Document	Publication Date	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages Or Relevant Figures Appear	T ⁶
		Country Code ³ -Number ⁴ -Kind Code ⁵ (if known)	MM-DD-YYYY			
/HS/		DE 196 52 463 C2	06-18-1998	Friedrich-Schiller-Universitat	Abstract	✓
/HS/		DE 198 32 830 A1	04-29-1999	Hewlett-Packard Co.		
/HS/		EP 0 450 560 B1	10-09-1991	Sumitomo Electric Ind.		
/HS/		EP 1 146 367 A2	10-17-2001	Berg Electronics Mfg. BV		
/HS/		EP 1 146 367 A3	05-12-2004	Berg Electronics Mfg. BV		

**Examiner
Signature**

/Hemang Sanghavi/

Date
Considered

05/13/2007

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Sheet 2	of 2	Attorney Docket Number	TYR-P0002

NON PATENT LITERATURE DOCUMENTS			
Examiner Initials*	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
/HS/		KUFNER M et al., "Microlenses in PMMA with High Relative Aperture: A Parameter Study", Pure and Applied Optics UK, vol. 2, no. 1, 1993, pages 9-19, XP002317582 ISSN: 0963-9659	
/HS/		BECKER, E W et al., "Fabrication of Microstructures with High Aspect Ratios and Great Structural Heights by Synchrotron Radiation Lithography, Galvanoforming, and Plastic Moulding (Liga Process)", Microelectronic Engineering, Elsevier Publishers BV., Amsterdam, NL, vol. 4, no. 1, May 1, 1986, pp. 35-56, XP000051563, ISSN: 0167-9317	

Examiner Signature	/Hemang Sanghavi/	Date Considered	05/13/2007
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